

# ISO/TR 22335:2007-07 (E)

## Surface chemical analysis - Depth profiling - Measurement of sputtering rate: mesh-replica method using a mechanical stylus profilometer

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<b>Contents</b>		<b>Page</b>
Foreword .....		iv
Introduction .....		v
1	Scope .....	1
2	Terms and definitions .....	1
3	Symbols and abbreviated terms .....	2
4	Principle .....	2
5	Procedure .....	2
5.1	Generating the replica pattern .....	2
5.2	Measurement of sputtered crater depth using a stylus profilometer .....	8
5.3	Estimation of sputtering rate .....	11
6	Summary of round-robin results .....	11
Annex A (informative) Geometry of specimen surface and ion gun .....		12
Annex B (informative) Dependence of replica patterns on mesh-opening size .....		15
Bibliography .....		18